We claim:

- 1. An optoelectronic package comprising:
 - a base chip, the chip comprising a base chip V-groove;
 - a fiber array, the array comprising an array V-groove formed in a rear portion and a front portion of the array;
 - a first wick stop disposed between the rear and front portions; and
 - an optical fiber, having an angled endface, disposed in both V-grooves to substantially couple the chip and array.
- 2. The optoelectronic package as in claim 1 wherein the array further comprises a sealing lid.
- 3. The optoelectronic package as in claim 2 wherein the sealing lid comprises a monolithic sealing lid.
- 4. The optoelectronic package as in claim 1 wherein the base chip further comprises an etch stop layer under the laser.
- 5. The optoelectronic package as in claim 4 wherein the layer comprises SiO₂.
- 6. The optoelectronic package as in claim 4 wherein the layer comprises silicon nitrate.
- 7. The optoelectronic package as in claim 4 wherein the layer comprises AL₂O₃.
- 8. The optoelectronic package as in claim 1 wherein the array comprises a first pit and the chip comprises a second pit.
- 9. The optoelectronic package as in claim 1 further comprising an alignment sphere, wherein the sphere is disposed between the first and second pits.
- 10. The optoelectronic package as in claim 1 wherein the array comprises a middle portion bordered by the first wick stop and a second wick stop.
- 11. The optoelectronic package as in claim 1 wherein the base chip further comprises a surface device.
- 12. The optoelectronic package as in claim 11 wherein the surface device comprises a VCSEL.

- 13. The optoelectronic package as in claim 11 wherein the surface device comprises a photodetector.
- 14. A method for coupling optoelectronic packages comprising:

forming a base chip V-groove in a base chip;

forming an array V-groove in a rear portion and a front portion of a fiber array;

disposing a first wick stop between the rear and front portions; and

disposing an optical fiber, having an angled endface, in both V-grooves to substantially couple the chip and array.

- 15. The method as in claim 14 further comprising disposing a surface device on the base chip.
- 16. The method as in claim 15 wherein the surface device comprises a VCSEL.
- 17. The method as in claim 15 wherein the surface device comprises a photodetector.
- 18. The method as in claim 14 further comprising enclosing the surface device with a sealing lid.
- 19. The method as in claim 18 wherein the sealing lid comprises a monolithic sealing lid.
- 20. The method as in claim 14 further comprising forming an etch stop layer in the base chip.
- 21. The method as in claim 20 wherein the layer comprises SiO₂.
- 22. The method as in claim 20 wherein the layer comprises silicon nitrate.
- 23. The method as in claim 20 wherein the layer comprises AL₂O₃.
- 24. The method as in claim 14 further comprising forming a first pit on the array and a second pit on the base chip.
- 25. The method as in claim 24 further comprising disposing an alignment sphere between the first and second pits.
- 26. The method as in claim 14 further comprising forming a middle portion bordered by the first wick stop and a second wick stop.